

## Supplementary Materials for

### Synthesis of centimeter-scale high-quality polycrystalline hexagonal boron nitride films from the Fe flux

Yifei Li<sup>1</sup>, Xin Wen<sup>1</sup>, Changjie Tan<sup>1</sup>, Ning Li<sup>2,3</sup>, Ruijie Li<sup>1</sup>, Xinyu Huang<sup>1</sup>, Huifeng Tian<sup>1</sup>, Zhixin Yao<sup>1,4</sup>, PeiChi Liao<sup>1</sup>, Shulei Yu<sup>1</sup>, Shizhuo Liu<sup>1</sup>, Zhenjiang Li<sup>1</sup>, Junjie Guo<sup>4</sup>, Yuan Huang<sup>5</sup>, Peng Gao<sup>2,3,6</sup>, Lifan Wang<sup>7,8</sup>, Shulin Bai<sup>1</sup>, and Lei Liu<sup>1,6\*</sup>

<sup>1</sup>School of Materials Science and Engineering, Peking University, Beijing 100871, China

<sup>2</sup>International Center for Quantum Materials, School of Physics, Peking University, Beijing 100871, China

<sup>3</sup>Electron Microscopy Laboratory, School of Physics, Peking University, Beijing 100871, China

<sup>4</sup>Key Laboratory of Interface Science and Engineering in Advanced Materials, Ministry of Education, Taiyuan University of Technology, Taiyuan 030024, P. R. China

<sup>5</sup>Advanced Research Institute of Multidisciplinary Science, Beijing Institute of Technology, Beijing, 100081, China

<sup>6</sup>Interdisciplinary Institute of Light-Element Quantum Materials and Research Center for Light-Element Advanced Materials, Peking University, Beijing 100871, China

<sup>7</sup>Beijing National Laboratory for Condensed Matter Physics, Institute of Physics, Chinese Academy of Sciences, Beijing 100190, China

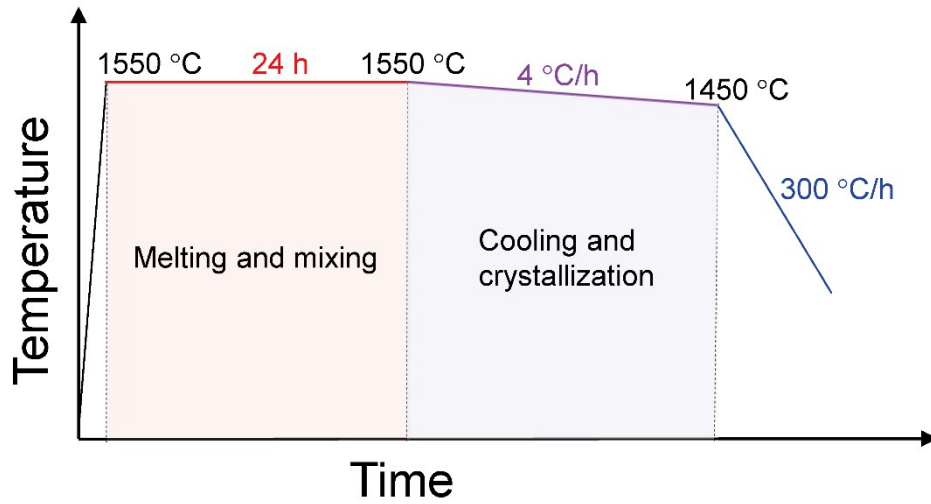
<sup>8</sup>Songshan Lake Laboratory for Materials Science, Dongguan 523000, China

\*Correspondence: [l\\_liu@pku.edu.cn](mailto:l_liu@pku.edu.cn);

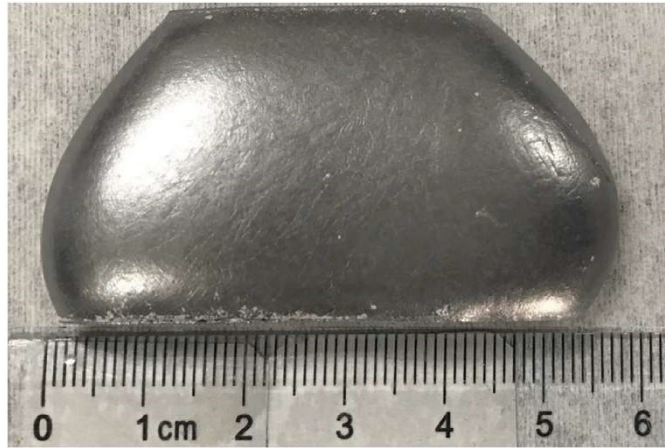
### Supplementary Note 1: Laser beam radius

The radius of the laser beam spot (objective lens  $100\times$ ) is an essential parameter for the thermal conductivity measurement, which was obtained by performing a micro-Raman scan across a smooth cleaved edge of an Au-covered Si substrate. Figure S6a-b displays the optical microscopy image of the Si edge and the corresponding Raman mapping of the Si Raman peak at  $520.7\text{ cm}^{-1}$  with a step size of  $0.1\text{ }\mu\text{m}$ . The measured intensity ( $I$ ) is proportional to the total laser power incident on the sample. Figure S6c shows the measured  $I$  as a function of the distance ( $x$ ) of the laser beam to the boundary.

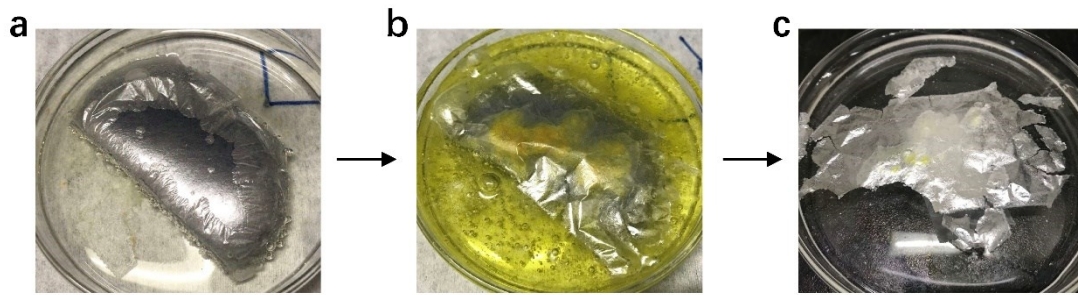
A Gaussian function  $\exp\left(-x^2/r_0^2\right)$  was used to fit the slope  $dI/dx$  to calculate  $r_0$ , which is estimated to be  $0.31 \pm 0.01\text{ }\mu\text{m}$ .



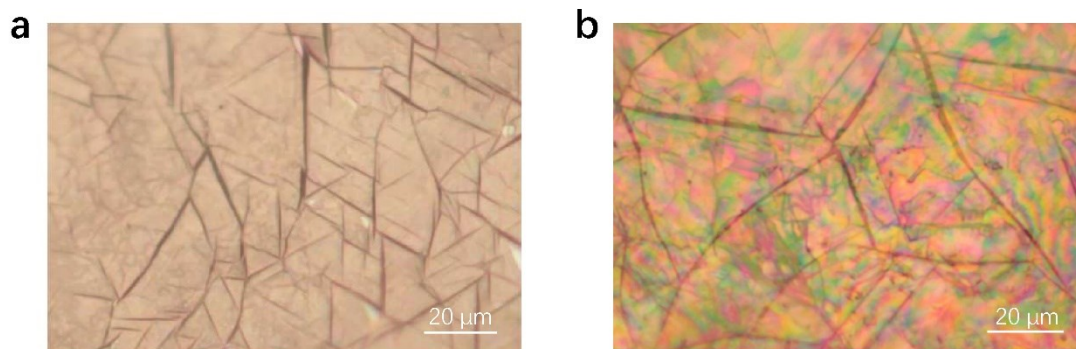
**Supplementary Figure 1 Temperature profile for h-BN crystal growth. The sample zone keeps at 1550 °C for 24 hours (red line), and then cools down to 1450 °C at a rate of 4 °C/hour (purple line), followed by quickly quenching (300 °C/hour) to room temperature (blue line).**



**Supplementary Figure 2 Representative optical image of one Fe ingot covered with hBN films.**



**Supplementary Figure 3 Optical images of the exfoliation process. a,** One Fe ingot covered with hBN film is immersed into the hydrochloride acid, and the hBN film starts to be exfoliated from the ingot immediately. **b,** The hBN film is wholly separated from the ingot about 1 hour later. **c,** The h-BN film is transferred and washed by the deionized water.

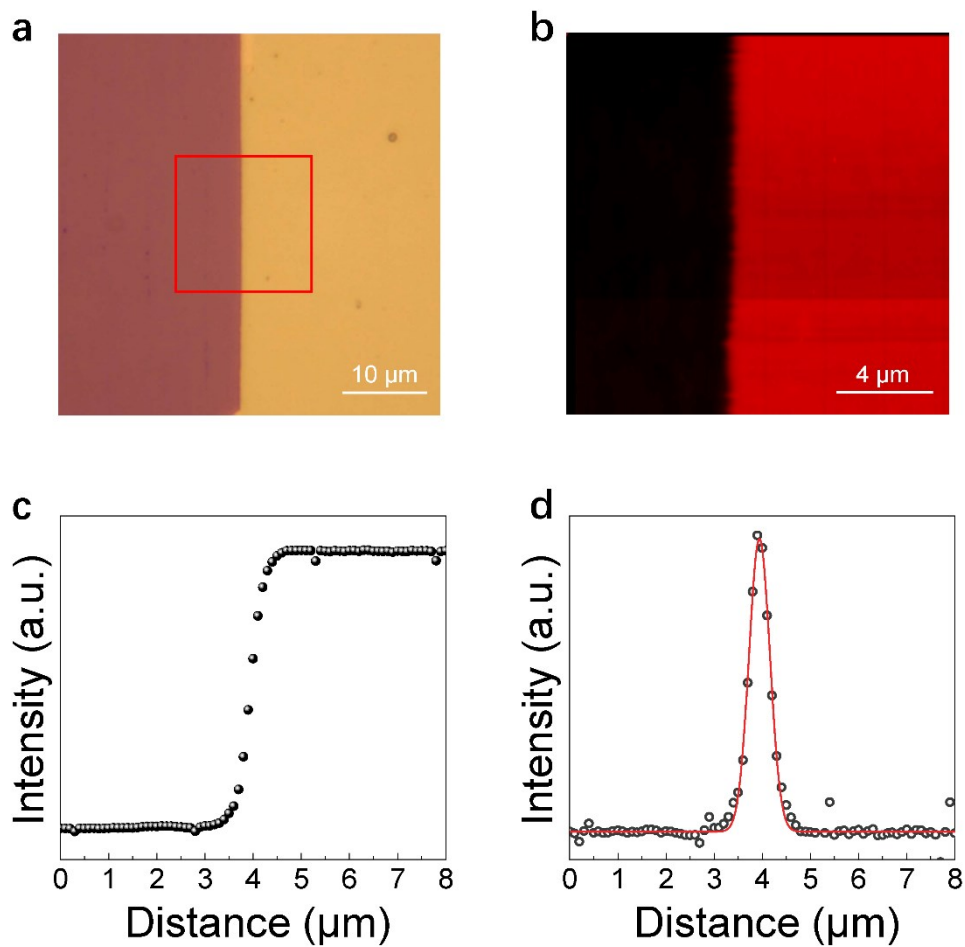


**Supplementary Figure 4 Optical microscopy images of hBN films grown at different %B.**

**a**, h-BN films with 2.4% of %B, showing the uniform thickness; **b**, h-BN films with less than 2.4% of %B, showing uneven thickness-induced colorful surface.

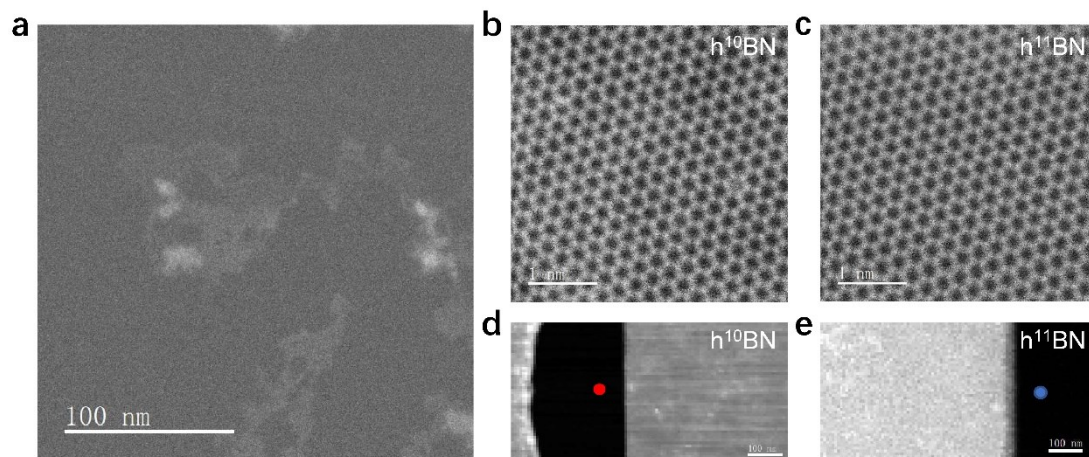


**Supplementary Figure 5 Optical image of the product with 25.3% of %B, showing original powder morphologies after the growth.**



**Supplementary Figure 6 Raman mapping of Si chip partially coated by Au and fitting results.** **a**, Optical microscopy image of the boundary w/ and w/o Au coating on a Si substrate; **b**, Raman mapping of the Si peak at 520.7  $\text{cm}^{-1}$  in the squared area in **a**; **c**, Intensity distribution of Si Raman peak across the boundary; **d**, Corresponding Gaussian fitting results of intensity distribution, suggesting  $0.31 \pm 0.01 \mu\text{m}$  of the radius of the laser beam spot.





**Supplementary Figure 7 Illustration of the STEM-EELS acquisition method.** **a**, HAADF image of h<sup>11</sup>BN at the large field of view; **b**, **c**, the unprocessed atomic resolution HAADF image of h<sup>10</sup>BN and h<sup>11</sup>BN, respectively; **d**, **e**, the low-magnification HAADF image of h<sup>10</sup>BN and h<sup>11</sup>BN respectively. The red and blue disk in **d** and **e** are the acquisition positions of STEM-EELS corresponding to Fig. 3c.